

ABSTRACT OF THE DISCLOSURE

A reticle stage moves while holding the reticle.
A stage controller detects the acceleration of the
5 reticle stage based on the results of detection of an
laser interference system. A main control system
controls movement of the reticle stage so that the
acceleration detected by the reticle stage becomes
within a predetermined range of acceleration of the
10 reticle stage where offset will not occur in the
reticle. An image of the pattern formed on the reticle
is transferred to a wafer through a projection optical
system while synchronously moving the reticle and the
wafer.

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